

Subt. For, PTO-1449				Docket Number 100718.418 (MIC-76)	Application Number 09/652,630
INFORMATION DISCLOSURE IN AN APPLICATION <i>(Use several sheets if necessary)</i>				Applicant David A. Cathey et al.	
Sheet	1	OF	1	Filing Date August 31, 2000	Group Art Unit 2879

Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)		
KIN	A	Guerin, L. J. et al., "SU-8 photoepoxy: A new material for FDP or PDP applications." Institute for Microsystems, Swiss Federal Institute of Technology, Switzerland, 53-54
KIN	B	Despont, M. et al., "HIGH-ASPECT-RATIO, ULTRATHICK, NEGATIVE-TONE NEAR-UV PHOTORESIST FOR MEMS APPLICATIONS," Proc. of the 10 th IEEE Int'l Workshop of Micro Electromechanical Systems (MEMS '97), Jan. 26-30, 1997, Nagoya, Japan
KIN	C	Lee, K. Y. et al., "Micromachining applications of high resolution ultrathick photoresist," J. Vac. Sci. Technol. B. 13(6), Nov/Dec 1995, pp. 3012-3016
KIN	D	Lorenz, H. et al., "Mechanical Characterization of a New High-Aspect-Ratio Near UV-Photoresist," Swiss Federal Institute of Technology, Switzerland

EXAMINER Kenneth J. Ramsey Primary Examiner	DATE CONSIDERED 4/30/03
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Sheet 1 of 1

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE (Modified) PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary) (37 CFR 1.98(b))				ATTY DOCKET NO. 100.718.418 (MIC-76)	SERIAL NO. 09/652,630						
				APPLICANT Cathey et al.							
				FILING DATE 08-31-2000	GROUP 2879						
U.S. PATENT DOCUMENTS											
EXAMINER INITIALS	PATENT NUMBER			ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE			
10911	5	6	5	8	3	2	08/19/97	Bernhardt et al			
10911	5	2	7	5	7	9	01/04/94	Tillotson et al			
10911	5	2	4	2	6	4	09/07/93	Poco			
FOREIGN PATENT OR PUBLISHED PATENT APPLICATION											
	DOCUMENT NUMBER			PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION			
								YES	NO		
OTHER DOCUMENTS (Including Author, Title, Date, Relevant pages, Place of Publication)											
10911	Lorenz et al, <i>Sensors & Activators</i> , A64:33-39 (1998).										
10911	Lorenz et al, <i>J. Micromech. Microeng.</i> , 7:121-124 (1997).										
10911	Ulrich, <i>Chemtech</i> , pages 242-249 (April 1988).										
10911	Shoup, <i>Colloid Interface Science</i> , 3:63-69 (1976).										
10911	<i>Ultrastructure Processing of Ceramics, Glasses, and Composites</i> , Hench and Ulrich, eds., Wiley-Interscience Publication, pages 70-87.										
EXAMINER	Kenneth J. Ramsey			DATE CONSIDERED		4/30/03					
	Primary Examiner										

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.